CAMT Seminar

– Student Seminar –
“Molecular dynamic simulations for determining carbon etching using two potential functions and automation of thermal distribution measurements of various substrates”

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Date: May 23, 2019 (Tue) 11:00-12:00
Location: Main Conference Room (1st floor), Bldg. A12
Center for Atomic and Molecular Technologies (CAMT)
(A12 棟 1 階会議室)

Abstract:
This presentation will show what exactly has been done in the past weeks. Simulations were done using the original van der Waals potential at first and later done using the newer Grimme potential. A program was created in order to more easily look at the thermal distribution of an impacting atom and the effect it has on its surrounding for all the individual shots was also discussed. A comparison of the yield was made between experimental results and the newer Grimme simulations, showing the simulation to have a lower etching yield than the experiments show.

(Host: Satoshi Hamaguchi Ext：7913)